

Ion Beam Source IBS - 400

Extended ion source IBS-400 is a gas-discharge source of working gas ions with an energy of 300-2500 eV. The principle of operation is an accelerator with an anode layer (UAS).

IBS-400 is designed for a wide range of applications: ion cleaning, etching, polishing, surface modification.



Parameter	Value
Beam shape	rectangular, hollow
Beam size (L x W x T)	370 x 42 x 5 mm

Length x Width x Thickness

Supply voltage	500 – 5000 V
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The average ion energy of the beam is approximately equal to half the supply voltage

Maximum beam current	600 mA
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For working gas - argon at a flow rate of not more than 2.0 l / h

Maximum voltage	5500 V
Maximum operating current	1000 mA
Maximum gas consumption	5,0 l / h
Maximum coolant consumption	1 l / min
Maximum working pressure in the chamber	10 Pa
Chamber working pressure range	0,001-1 Pa
Weight	no more than 6 kg

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It is produced in several versions.

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basic dimensions, versions

